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PATENT
3731-0144P

IN THE U.S. PATENT AND TRADEMARK OFFICE

Applicant: Victor KATSAP et al.

Appl. No.: 09/414,004

Group: 2881

Filed: October 7, 1999

Examiner: K. Fernandez

For: LENS ARRAY FOR ELECTRON BEAM LITHOGRAPHY TOOL
(as amended)

AMENDMENT

Assistant Commissioner for Patents
Washington, D.C. 20231

April 9, 2001 (Monday)

Sir:

In response to the Office Action mailed on February 8, 2001, the following amendments and remarks are respectfully submitted in connection with the above-identified application.

IN THE SPECIFICATION

In the Title, change

07/10/2001 SSURLES-48000003-301139 "ILLUMINATION SYSTEM FOR ELECTRON BEAM LITHOGRAPHY TOOL".

01 FC:117 890.00 CH
02 FC:102 240.00 CH
03 FC:103 198.00 CH

--LENS ARRAY FOR ELECTRON BEAM LITHOGRAPHY TOOL--.

IN THE SPECIFICATION

Please replace the paragraph beginning on page 4, line 29, with the following rewritten paragraph: